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On the cover...

Cover design by Dinia Agrawala. Counter-clockwise starting from the top: Frosch (left) and Derick (see p. 31); Shockley, the day after hearing about the Nobel Prize (see p. 37); a transparency used by Frosch at the end of his lectures in the mid-1950s. The letters were etched on a 3/4-inch silicon wafer using the oxide-masking technique he developed with Derick; the "Fairchild Eight" (see p. 38); one of the earliest prototype integrated circuits (see p. 40); and the Intel 1103 memory chip (see p. 49).